

BEST AVAILABLE COPY

5,239,447

ular aspect of the present invention, a
onic devices are disposed in a stack
electronic device has an edge having
location thereon and wherein elec-
arranged to expose the contact loca-
edge by forming a stepped surface
side of the electronic device stack.
particular aspect of the present in-
onic device stack is disposed against a
a plurality of contact locations
at least one substrate contact loca-
connected to at least one contact loca-

particular aspect of the present inven-
tional interconnection between the chip
and the substrate contact location
local conductor bearing elastomeric
posed between the chip contact loca-
rate contact location.

a particular aspect of the present in-
tronic device stack has at least one
face for thermal connection to a heat

BRIEF DESCRIPTION OF THE DRAWINGS

matic representation of one chip hav-
ons thereon along an edge electrically
substrate having contact locations
the chip subtends a non-orthogonal
to the substrate.
plurality of chips stacked in a non-
ment.

in elongated cylinder having electri-
hands thereon which is used as the
hector between the chip contact loca-
rate contact locations in the embodi-
FIGS. 4 and 5.

chip stack of FIG. 2 with the struc-
the electrical interconnection means
disposed in connection with the chip

arged view of the electrical intercon-
FIG. 4.

on-orthogonal stacking of chips along
pendicular directions.

amatically shows an apparatus and
xing the stacked structure described

a stacked structure electrically con-
tacts by an interconnection means
ed conductors in an elastomer.

another embodiment of the stepped
esent invention with contact location
y connected to substrate contact loca-
a.

BRIEF DESCRIPTION OF THE
PREFERRED EMBODIMENT

view of an embodiment of the present
ic 2 has at least one contact location 4
ic device 6 has at least one contact
or surface 8 along an edge 10. Elec-
as an opposite surface 7. Electronic
an angle 12 with respect to substrate
non-orthogonal angle, that is not 90
ic device 6 contact location 8 is elec-
to substrate contact location 4 by
section means 13 which can be metal-

lized elastomeric body as described herein below, and
which can also be a solder interconnection; wireboard
array, patterned conductive epoxy; liquid metal; spring
loaded or spring contacts; e.g., fuzz buttons or any
other electrical interconnection means.

FIG. 2 shows a plurality of electronic devices 14, 16,
18 and 20, which are stacked one on top of each other.
Electronic devices 16, 18 and 20 are disposed in intimate
contact with respect to each other. Electronic device 14
is shown spaced away from electronic device 16 for the
purpose of showing how the electronic devices are
stacked. FIG. 2 shows four electronic devices in a stack.
The structure of FIG. 2 is not limited to four, there can
be any number of electronic devices in a stack. Each

electronic device can be any type of an electronic
device such as a dielectric material having electrically
conducting lines therein, for example a printed circuit
board and a metallized ceramic. Alternatively, elec-
tronic devices of FIG. 2 can be semiconductor chips,
for example, silicon chips and gallium arsenide chips.

Each electronic device is stacked onto an adjacent
device with an edge of each device set back by a distance
22 from the adjacent device. The setback is preferably
the same between each device. Each device has at least

one contact location 24, preferably a plurality of
contact locations along an edge region 26. The setback
22 results in the contact locations 24 being exposed for
each device. In the preferred embodiment, the top de-
vice in the stack 14 is preferably a dummy device, that
is having no electrical function but having a structural
function but this is not necessary. If the setback 22 of

each device is equal, the structure has a stack angle 28.
The resultant stacked chip structure 30 has a stepped or
staircased edge 32 with exposed electronic device

contact locations and if the electronic devices are of the
same dimension, there is a corresponding stepped or
staircased surface 34 which can have additional chip
contact locations or can be without device contact loca-
tions. The structure of FIG. 2 shows each electronic

device stepped back from an adjacent electronic device
along the same direction 36. Between each adjacent
electronic device such as 16 and 18 there is preferably
an adhesive, such as an epoxy cement to keep each
electronic device of the stack 30 physically adhering

together. An adhesive layer is not shown in FIG. 2.
Alternatively, the electronic devices of the stack 30 can
be mechanically held together by a clamp. There may
also be spacers placed between the devices.

FIG. 4 shows an electronic device stack 30 having
nine electronic devices 40 in the stack. Electronic de-
vice stack 30 edge 32 having the exposed electronic
device contact locations is disposed adjacent surface 42
of substrate 44. Surface 42 of substrate 44 has a plurality
of contact locations 46 thereon. Contact locations 46 are
electrically interconnected to contact locations 24 of

electronic devices 40 by means 48 which can be a plu-
rality of solder mounds disposed between electronic
device contact locations 24 and a corresponding sub-
strate contact location 46. Where solder mounds are
used the controlled-collapse-chip-connection methods
described in U.S. Pat. Nos. 3,401,126 and 3,429,640 to
Miller, the teachings of which are incorporated herein
by reference. Stepped edge 34 of electronic device stack
30 which is opposite to stepped edge 32 is disposed in to
a stepped groove 36 in the surface of heat sink 38. The
stepped surface 34 of electronic device stack 30 pro-
vides an enlarged surface area than would be provided
if each electronic device were stacked orthogonally on

electronic device is located on the
corresponding step 130 fixture 140 and not
the previous electronic device.

(16) Step 5--Go to step two to load the
next electronic device.

(17) FIG. 8 is a diagrammatical cross
section, similar to that of FIG. 5,
showing an alternate means for electrically
interconnecting the electronic
device contact pads 224 in electronic
devices 240. Wires 250 are bonded at one
end 252 thereof to the electronic device
contact pads 224. The wires can be,
for example, of Au, Al and Cu, for example
of 0.001 to 0.003 inch diameter.
The joint between ends 252 and contact
locations 224 can be a wire bond. The
bonds can be a flattened ball bonds or wedge
bonds both of which are commonly
practiced in the art. The wires are bent at
an angle to the electronic devices
surface 254 by jogging the bonder platform
that the part rests upon after to
bond is made. The end 256 of wire 250 is
severed at a predetermined position.
The ends 256 may be bent, laser-formed into
ball shapes or left as straight
wires. End positions may be manipulated to
assure a given grid geometry for
contact to substrate contact locations 246.
The array is then encapsulated in
an elastomeric, e.g. silicone, material
leaving the ends of the leads free.
There are two preferred methods for
encapsulation of the leads. The first is
to fixture the array so that the balls form
a plane at the top of the part, and
then to introduce a controlled volume of
liquid encapsulant into the area of
the leads. The spaces between the leads
fills by capillary attraction and
stops at the base of the balls. The liquid
is then cured at elevated
temperature. The second method is to first
encase the lead ends in a water
soluble solid, i.e., sugar, by dipping into
the liquid form and then drying.
Liquid elastomer is then forced under
pressure into the space to be filled and
cured. The water soluble cap is then
dissolved away exposing the ends of the
leads. The assembly may be pressed to the
substrate or solder bonded as
described above to the substrate contact
locations 246 on substrate 244.

(18) FIG. 9 shows another embodiment of
the stepped stack of chips shown in
FIG. 2. The stack is disposed on a
substrate 260 having a plurality of

col 7, L 99-51

BEST AVAILABLE COPY

U.S. Patent

Aug. 24, 1993

Sheet 1 of 8

5,239,447

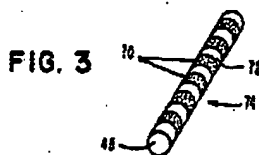
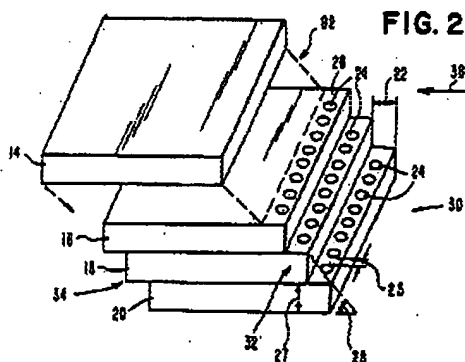
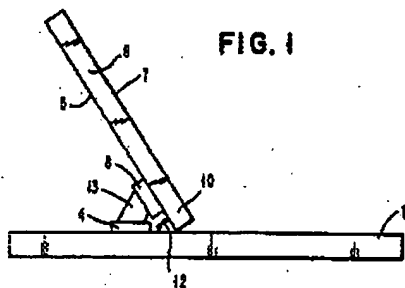


FIG. 1

FIG. 2

FIG. 3

In a more particular aspect of the present invention, a plurality of electronic devices are disposed in a stack and wherein each electronic device has an edge having at least one contact location thereon and wherein electronic devices are arranged to expose the contact location on each chip edge by forming a stepped surface along at least one side of the electronic device stack.

In another more particular aspect of the present invention, the electronic device stack is disposed against a substrate having a plurality of contact locations thereon, there being at least one substrate contact location electrically connected to at least one contact location.

Another more particular aspect of the present invention is the electrical interconnection between the chip contact location and the substrate contact location through an electrical conductor bearing elastomeric body which is disposed between the chip contact location and the substrate contact location.

In another more particular aspect of the present invention, the electronic device stack has at least one other stepped surface for thermal connection to a heat dissipation means.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 is a schematic representation of one chip having contact locations thereon along an edge electrically connected to a substrate having contact locations thereon wherein the chip subtends a non-orthogonal angle with respect to the substrate.

FIG. 2 shows a plurality of chips stacked in a non-orthogonal arrangement.

FIG. 3 shows an elongated cylinder having electrically conducting bands thereon which is used as the electrical interconnector between the chip contact locations and the substrate contact locations in the embodiments shown in FIGS. 4 and 5.

FIG. 4 shows the chip stack of FIG. 2 with the structure of FIG. 3 as the electrical interconnection means and a heat sink disposed in connection with the chip stack.

FIG. 5 is an enlarged view of the electrical interconnection means of FIG. 4.

FIG. 6 shows non-orthogonal stacking of chips along two mutually perpendicular directions.

FIG. 7 diagrammatically shows an apparatus and method for fabricating the stacked structure described herein.

FIG. 8 shows a stacked structure electrically connected to a substrate by an interconnection means formed from formed conductors in an elastomer.

FIG. 9 shows another embodiment of the stepped structure of the present invention with contact locations thereon electrically connected to substrate contact location by wire bonds.

DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENT

FIG. 1 is a side view of an embodiment of the present invention. Substrate 2 has at least one contact location 4 thereon. Electronic device 6 has at least one contact location 8 on major surface 5 along an edge 10. Electronic device 6 has an opposite surface 7. Electronic device 6 subtends an angle 12 with respect to substrate 2. Angle 12 is a non-orthogonal angle, that is not 90 degrees. Electronic device 6 contact location 8 is electrically connected to substrate contact location 4 by electrical interconnection means 15 which can be metal-

lized elastomeric body as which can also be a solder array, patterned conductive loaded or spring contacts, other electrical interconnection means.

FIG. 2 shows a plurality 18 and 20, which are stacked. Electronic devices 16, 18 and 20 are shown spaced away from each other with respect to each other. FIG. 2 shows four devices stacked. The structure of FIG. 2 is shown in FIG. 3.

FIG. 3 shows an elongated cylinder 24 having electrically conducting bands 26 thereon which is used as the electrical interconnector between the chip contact locations and the substrate contact locations in the embodiments shown in FIGS. 4 and 5.

FIG. 4 shows the chip stack of FIG. 2 with the structure of FIG. 3 as the electrical interconnection means and a heat sink 30 disposed in connection with the chip stack.

FIG. 5 is an enlarged view of the electrical interconnection means of FIG. 4. FIG. 6 shows non-orthogonal stacking of chips along two mutually perpendicular directions.

FIG. 7 diagrammatically shows an apparatus and method for fabricating the stacked structure described herein. FIG. 8 shows a stacked structure electrically connected to a substrate by an interconnection means formed from formed conductors in an elastomer.

FIG. 9 shows another embodiment of the stepped structure of the present invention with contact locations thereon electrically connected to substrate contact location by wire bonds.

FIG. 10 is a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 11 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 12 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 13 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 14 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 15 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 16 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 17 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 18 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 19 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 20 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 21 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.

FIG. 22 shows a perspective view of a stepped structure 40. It consists of a series of steps 42 and 44. Contact locations 46 are on the top surface, and contact locations 48 are on the side surfaces. Wire bonds 70 connect the contact locations 46 to a substrate 72.